EXICOR® GEN SERIES



Aunion Tech Co.,Ltd

1850-166-2513

021-510-83793

info@auniontech.com

www.auniontech.com

PRODUCT BULLETIN



EXICOR GEN SERIES

Ultra-low retardation measurements. Award Winning. Reliable.



EXICOR® GEN SERIES



Aunion Tech Co.,Ltd

1850-166-2513

021-510-83793

info@auniontech.com

www.auniontech.com

PRODUCT BULLETIN

Applications

- Quality control metrology
- Low-level birefringence measurements of
 - Display glass
 - LCD
 - Large irregular shaped planar glass and plastic
 - Plastic film

System Options

- Scan In Motion (SIM)
- Keep Out Barrier
- Manual or Auto Tilt Stage
- Thickness and Warpage Sensors on GEN5 or GEN6

Significant Features

- Unprecedented sensitivity in low-level birefringence measurement
- Simultaneous measurement of birefringence magnitude and angle
- Precision repeatability
- High-speed measurement
- No moving parts in the optical system
- Automatic mapping of variable-sized optical elements
- Photoelastic modulator technology
- · Simple, user-friendly operation



EXICOR® GEN SERIES



Aunion Tech Co.,Ltd

1850-166-2513 info@auniontech.com 021-510-83793 www.auniontech.com

PRODUCT BULLETIN

GEN Specifications

Retardation Range 0.005nm to 300 nm

Resolution¹ 0.001 nm

Repeatability¹ $\pm 0.01 \text{ nm}$ (Retardation < 1 nm) or $\pm 1\%$ (Retardation > 1 nm)

Angular Resolution/Repeatability $0.01^{\circ}/\pm0.05^{\circ}$ Measurement Time Up to 10 pps Wavelength 632.8 nm Spot size \sim 1 mm typical

Demodulation Analysis Technique Hinds Instruments Signaloc[™] Lock-in Amplifiers

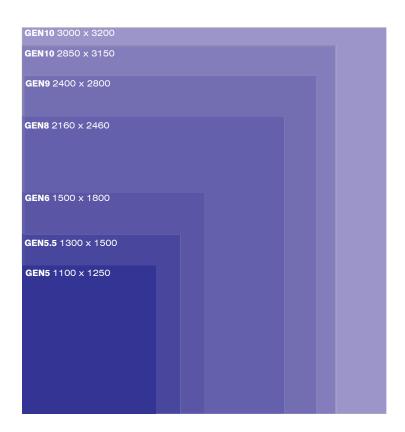
Measurement Units nm (retardation), ° (angle)

 Maximum Sample Size (mm)
 1175 x 1375
 1600 x 2000
 2500 x 3000

 Maximum Scan Area (mm)
 1100 x 1300
 1575 x 1925
 2400 x 2800

GEN System Glass Measurements

| GENERATION | GLASS SIZE |
|------------|-------------|
| 5 | 1100 x 1250 |
| | 1100 x 1300 |
| 5.5 | 1300 x 1500 |
| 6 | 1500 x 1850 |
| 8 | 2160 x 2450 |
| | 2200 x 2500 |
| 9 | 2400 x 2800 |
| 10 | 2580 x 3050 |
| | 3000 x 3200 |



¹ Typical performance at 5nm Retardation

² Maximum data collection speed. Sample XY scan time dependent on stage movement parameters.

³ Custom wavelengths available